Abstract

Tunable MEMS Device

A MEMS device includes a resonant member 17 supported from a substrate 15a, 15b. The resonant member includes a layer of piezoelectric material 12, and electrodes 11a, 11b, 11c, 13 for applying electric fields to respective parts of the layer of piezoelectric material 12. A control circuit controls electric fields applied to the piezoelectic layer 12, to vary the frequency and/or the quality factor of the resonance. Exemplary uses of the device are as sensors, transducers or filters.

[Fig. 1(a)]